



APPLICATIONS

- Wafer Processing & Cleaning
- Wafer Stripping
- Laboratory Applications
- Bake & Develop Stations
- Etching

Designed for Laboratory processing of 6" and smaller substrates.

JST's Vertical Laminar Flow

Workstation (VLF) is a modular workstation designed for manually processing 6" or smaller wafers in a class 100 or better cleanroom. The unique exhaust design pulls laminar air evenly across the work surface maintaining the same clean laminar air inside the work area as in the clean room. Particles and vapor fumes from the chemistry are pulled away from the operator, through the deck and exhaust slots to the facility exhaust system.

The workstation's plenum houses the process and rinse baths mounted on removable support bars. Plumbing components are located for easy access.

Electrical controllers, switches and flow meters are located in a purged electrical enclosure that provides a safe, easily accessible area for servicing.

JST's VLF is designed to be incorporated with JST's process and rinse baths to customize a workstation to your particular application. Let JST's experienced engineering staff help you configure a system that is just right for you.

STANDARD FEATURES

- Removable Sloped Deck
- 304L or 316L Stainless Steel
- White Polypropylene
- FM Approved PVC-C Material
- Purged Electrical Compartments
- Exhaust Failure Alarm
- Emergency Power Off
- Secondary Containment
- Seismic Anchors
- Lockout/Tagout Box
- Front & Side Safety Shields

OPTIONAL FEATURES

- Rear Access Compartment
- Front Roll Switches
- Dedicated Drains
- Drain to Carboy
- Fire Suppression
- Storage Compartment
- SEMI S2 Certification
- Emergency Power Off
- CE Marking
- 3rd Party Electrical Inspections

Wet Processing and Precision Cleaning Technology